



17628  
PATENT

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant : Paul B. Mirkarimi et al.      Docket No. : CIL-10972  
Serial No. : 10/086,614      Art Unit : 1762  
Filed : March 1, 2002      Examiner : W. Markham  
For : Ion-Assisted Deposition Techniques For  
The Planarization Of Topological Defects

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

CERTIFICATE OF MAILING UNDER 37 CFR 1.8(a)

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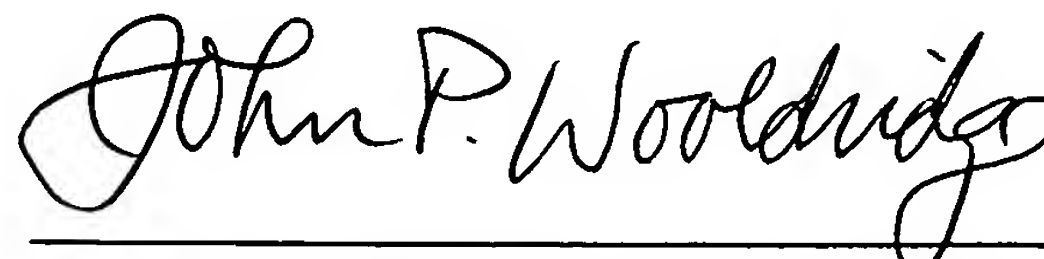
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